Amendments to the Specification:

Please replace paragraph 2 of page 15 in original application with the following amended paragraph:

[Paragraph 2, page 15] Hence, according to still another embodiment of the present invention, as shown in Figs. 6 (a) and (b), a de-actuation device (80) is added to switch (50) and is disclosed to de-actuate the switch (50). In Fig. 6(a), all numbered elements illustrated in element (50) have the same meaning as the ones depicted in Figs. 5(a) and 5(b). In this de-actuation device (80), a third de-actuation electrode (81) is deposited on a second substrate (82) in order to de-actuate the freestanding cantilever (58) during switching from an On-state to an Off-state. The third de-actuation electrode (81) is aligned and mounted facing the cantilever (58), which is fabricated and supported by the first substrate (51). To de-activate the microwave MEMS switch (50), the voltage applied between the first actuation electrode (60) and the second actuation electrode (61) is switched off and a second voltage is applied between the second actuation electrode (61), which is connected to the input transmission line (52), and the third de-actuation electrode (81) through a third de-actuation electrode line (83), both (81) and (83) are deposited on the second substrate (82). An electrostatic force will be induced between the cantilever (58) and the third de-actuation electrode (81), causing the cantilever (58) to break free from the contact with the output transmission line (53). Consequently, the electrostatically actuated microwave MEMS switch (50) can be de-activated without the limitation of the van der Wall force or the airflow problem.